

Title (en)  
POLISHING APPARATUS AND DRESSING METHOD

Title (de)  
POLIERVORRICHTUNG UND ABRICHTVERFAHREN

Title (fr)  
APPAREIL DE POLISSAGE ET PROCEDE DE DECRASSAGE

Publication  
**EP 1361933 A1 20031119 (EN)**

Application  
**EP 02700615 A 20020220**

Priority  
• JP 0201456 W 20020220  
• JP 2001043777 A 20010220

Abstract (en)  
[origin: WO02066207A1] The apparatus for polishing a substrate while pressing the substrate into sliding contact with the fixed abrasive, comprises: a light source (32) for dressing the fixed abrasive by light irradiation; and a device (41) for supplying a chemical agent or a chemical liquid for promoting the self-generation of abrasive particles in the dressing by light irradiation. The supply of a chemical agent or a chemical liquid onto the surface of fixed abrasive can promote or maintain dressing effect attained by the light irradiation. The chemical agent or the chemical liquid to be supplied preferably contains boron, particularly preferably a borate.

IPC 1-7  
**B24B 37/04**; **B24B 53/007**

IPC 8 full level  
**B24B 53/00** (2006.01); **B24B 53/007** (2006.01); **B24B 53/017** (2012.01)

CPC (source: EP KR US)  
**B24B 37/04** (2013.01 - KR); **B24B 37/24** (2013.01 - KR); **B24B 53/001** (2013.01 - EP US); **B24B 53/017** (2013.01 - EP KR US);  
**B24B 53/02** (2013.01 - KR)

Citation (search report)  
See references of WO 02066207A1

Designated contracting state (EPC)  
DE FR

DOCDB simple family (publication)  
**WO 02066207 A1 20020829**; EP 1361933 A1 20031119; KR 20030022105 A 20030315; US 2003100246 A1 20030529

DOCDB simple family (application)  
**JP 0201456 W 20020220**; EP 02700615 A 20020220; KR 20027012822 A 20020927; US 22177102 A 20020917